Method and device for monitoring sensors and for locating failures in an industrial process.

Patent number:

EP0537041

Publication date:

1993-04-14

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Classification:

- international:

B21B37/00; B21B33/00; G01D21/00; G05B9/02;

G05B23/02; B21B37/00; B21B33/00; G01D21/00;

G05B9/02; G05B23/02; (IPC1-7): B21B33/00; G05B9/02

- european:

B21B33/00; G05B9/02

Application number: EP19920402560 19920917 Priority number(s): FR19910012323 19911007 Also published as:

JP5273002 (A) FR2682208 (A

EP0537041 (B

Cited documents:

US4249238 US5047964

JP58155413

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Abstract of EP0537041

Method for monitoring an industrial process including a succession of steps P1 to Pn for transforming a product from an initial state Yo to a final state Yn, in which each step Pi and each state Yi are characterised by representative parameters, is characterised in that, for each step Pi, the parameters representative of the state Yi of the product are calculated with the aid of a mathematical model Fi representative of the said step, on the basis of parameters representative of the state Yi-1 of the product before the step and of the parameters representative of the step Pi; the parameters representative of the final state Yn of the product are measured; values of the calculated and measured parameters representative of the final state of the product are compared in order to determine therefrom deviations; and the values of the measured parameters are compared with tolerance brackets and the calculated deviations with tolerance thresholds in order to determine, in the event of disagreement, a malfunction of at least one sensor and/or of at least one step of the process.